

REMARKS/ARGUMENTS

1. Rejection of claims 1-3, 6-8, 10-14, 16-18 and 20-21 under 35 U.S.C. 103(a) as being unpatentable over Ledger et al. (5,515,167) in view of Strasbaugh et al. (US 2003/0134578):

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Claim 1:

Claim 1 is listed hereinafter for reference:

Claim 1 (previously presented) A wafer carrier for carrying a wafer, comprising:
a transparent base;

10 a conducting layer positioned on a bottom surface of the transparent base; and
a bonding layer positioned on a top surface of the wafer carrier for bonding the
wafer and the transparent base together;

wherein the wafer carrier is attracted by an electrostatic chuck via the
conducting layer.

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The wafer carrier of claim 1, which comprises a transparent base, a conducting layer positioned on a bottom surface of the transparent base, and a bonding layer positioned on a top surface of the wafer carrier for bonding the wafer and the transparent base together, is attracted by an electrostatic chuck via the conducting
20 layer. Specifically, the conducting layer is one of the wafer carrier's components, and disposed on the transparent base before the wafer carrier is attracted by the electrostatic chuck. This means the wafer carrier having the conducting layer, and the
electrostatic chuck are separated from the conducting layer before the wafer carrying
process.

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Considering Leger's teaching, the conducting layer 32 is part of the electrostatic
chuck 24. In col. 4, line 10-col. 5, line 55, Ledger describes that the conducting layer 32 is formed on the electrostatic chuck 32. For instance, Ledger specifies that the
conducting layer 32 is deposited on the electrostatic chuck 24 (col. 4, lines 58-60).
30 Also, he also teaches that the electrostatic chuck 24 is formed by first coating the
conducting film on the membrane 34, and then cementing the membrane 34 with the

chuck 24 (col. 5, lines 29-33; lines 42-47). This means the conducting layer 34, the membrane 34, and the chuck 24 are all combined together before the wafer carry process.

5 The wafer carrier of claim 1 is a media to carry a wafer. The wafer carrier has a conducting layer formed thereon so that the electrostatic chuck can attract the wafer carrier by electrostatic force, and a bonding layer to bond the wafer. The wafer is not adhered to the wafer carrier or the electrostatic chuck by electrostatic force. Compared with the wafer carrier of claim 1, Ledger's invention is an electrostatic chuck having
10 membrane and conducting layer formed thereon before the chuck attracts the wafer. It is common and required to have an electrode or conducting layer in the electrostatic chuck so that it can attract the wafer. The electrostatic chuck used to attract the wafer carrier in claim 1 also requires electrode or conducting layer, but they are not shown or described in detail because they are part of the electrostatic chuck, which is not the
15 point of the instant application.

The idea of the present application is to propose a wafer carrier that can be attracted by the electrostatic chuck because of its intact surface compared to the surface of the processed wafer.

20 In addition, Ledger's chuck attracts the wafer with electrostatic force so that the chuck has the electrode and the membrane thereon. Using the bonding layer to bond the wafer and the electrostatic chuck not only is unnecessary, but also change the principle of operation of Ledger's invention. See In re Ratti, 270 F.2d 810, 123 USPQ
25 349 (CCPA 1959). In the instant case, if the wafer is bonded to Ledger's chuck with a bonding layer, the conducting layer will be redundant and useless. The applicant believes doing so is meaningless and would change the principle of operation of Ledger's teaching.

30 Thus, Reconsideration of claim 1 is politely requested.

Claim 2-3, 6-8, and 10-11:

Claims 2-3, 6-8, and 10-11 are dependent on claim 1, and should be allowed if claim 1 is found allowable. Reconsideration of claims 2-3, 6-8, and 10-11 is therefore requested.

5 Claim 12:

Claim 12 is listed hereinafter for reference:

Claim 12 (previously presented) A wafer carrier adapted for use in a double-sided process for carrying a wafer, comprising:

a transparent base;

10 a conducting layer positioned on a bottom surface of the transparent base, wherein the wafer carrier is attracted by an electrostatic chuck via the conducting layer; and
a bonding layer positioned on a top surface of the transparent base for bonding the wafer and the transparent base.

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Claim 12 also includes the distinguishable limitations as claim 1. Reconsideration of claim 12 in view of the argument made to rejection of claim 1 is requested.

20 Claims 13-14, 16-18, and 20-21:

Claims 13-14, 16-18, and 20-21 are dependent on claim 12, and should be allowed if claim 12 is found allowable. Reconsideration of claims 13-14, 16-18, and 20-21 is therefore requested.

25 **2. Rejection of claims 4 and 15 under 35 U.S.C. 103(a) as being unpatentable over Ledger et al. in view of Strasbaugh et al. and further in view of Suzuki et al. (US 2003/0029565):**

Claim 4:

30 Claim 4 is dependent on claim 1, and should be allowed if claim 1 is found allowable. Reconsideration of claim 4 is therefore requested.

Claim 15:

Claim 15 is dependent on claim 12, and should be allowed if claim 12 is found allowable. Reconsideration of claim 15 is therefore requested.

5 **3. Rejection of claims 9 and 19 under 35 U.S.C. 103(a) as being unpatentable over
Ledger et al. in view of Strasbaugh et al., and further in view of Bollen et al.
(US 4,766,515):**

Claim 9:

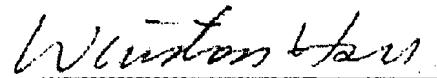
10 Claim 9 is dependent on claim 1, and should be allowed if claim 1 is found allowable. Reconsideration of claim 9 is therefore requested.

Claim 19:

15 Claim 19 is dependent on claim 12, and should be allowed if claim 12 is found allowable. Reconsideration of claim 19 is therefore requested.

Applicant respectfully requests that a timely Notice of Allowance be issued in this case.

20 Sincerely yours,



Date: 06/20/2007

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30 D.C. is 12 hours behind the Taiwan time, i.e. 9 AM in D.C. = 9 PM in Taiwan.)